

Diagram 1

Vertical measurement values

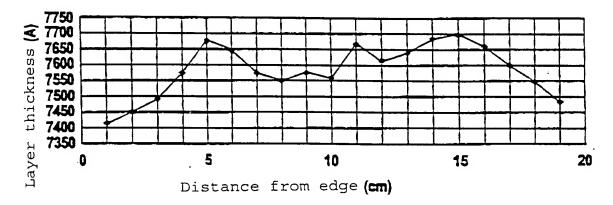
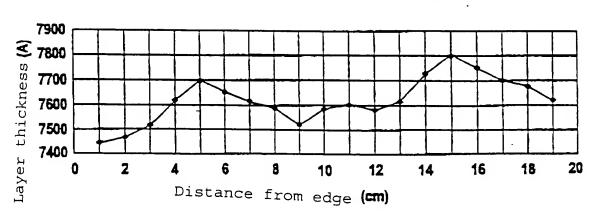


Diagram 2

Horizontal measurement values



Wafer profile after etching with ethylene glycol / HF (15%) in a spin etcher

Diagram 3

Vertical measurement values

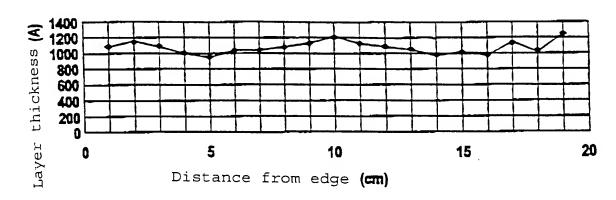
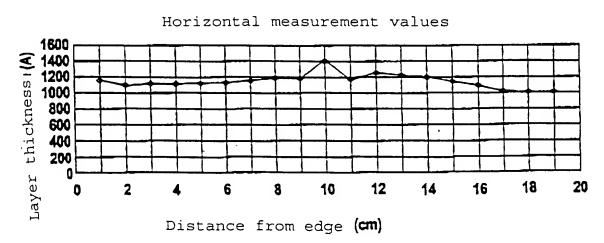


Diagram 4



Wafer profile after etching with ethylene glycol / glycerol / HF (15%) in a spin etcher

Diagram 5

Vertical measurement values

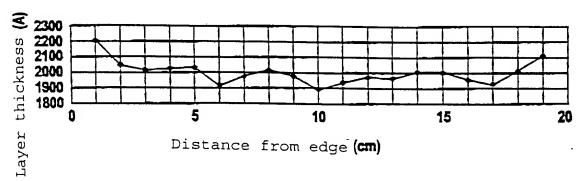


Diagram 6,

Horizontal measurement values

